hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail, in an envelope addressed to: MSAF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below.

Dated: July 1, 2005 Signature:

AF

Docket No.: 30205/39514

(PATENT)

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Geun Su Lee

Application No.: 10/718,959

Confirmation No.: 4436

Filed: November 21, 2003

Art Unit: 1752

For: Photoresist Polymer and Photoresist Composition

Containing the Same

Examiner: Sin J. Lee

## AMENDMENT IN RESPONSE TO FINAL OFFICE ACTION (37 C.F.R. §1.116)

MS AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

## **INTRODUCTORY COMMENTS**

In response to the final Office Action dated May 4, 2005, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 9 of this paper.